

AMENDMENTS TO THE CLAIMS

Please amend claims 6, 10 and 14, as follows:

Claims 1-4 (Cancelled)

5. (Previously Presented) The wafer-shipping device as claimed in claim 6, wherein the pressure inside the shipping box approximates atmospheric pressure.

6. (Currently Amended) A wafer-shipping device, comprising:
a shipping box for a wafer, the shipping box having at least one through hole;
a packaging bag to contain the shipping box; and
a dry inert gas filling the packaging bag and the shipping box to balance a pressure inside the shipping box and the atmospheric pressure in order to prevent the shipping box from deforming, the dry inert gas surrounding the wafer, wherein the dry inert gas is nitrogen.

7. (Previously Presented) The wafer-shipping device as claimed in claim 6, wherein after pumping an air out of the shipping box and the packaging bag, the dry inert gas fills the shipping box and the packaging bag.

Claim 8 (Cancelled)

9. (Previously Presented) The wafer-shipping device as claimed in claim 10, wherein the pressure inside the shipping box approximates atmospheric pressure.

10. (Currently Amended) A wafer preserver, comprising:
a container having at least a vacant space;
a wrapping for packaging the container; and
a gas filling the container and surrounding the wafer to balance a pressure inside the container and the atmospheric pressure in order to prevent the container from deforming, wherein the gas is dry nitrogen.

11. (Previously Presented) The wafer preserver as claimed in claim 10, wherein after pumping an air from the container and the wrapping, the gas fills the container and the wrapping.

Claim 12 (Cancelled)

13. (Previously Presented) The semiconductor preserver as claimed in claim 14, wherein the pressure inside the first space approximates atmospheric pressure.

14. (Currently Amended) A semiconductor preserver, comprising:

a first space for containing the semiconductor;

a second space formed by a gas-proof material surrounding the first space;

a vacant space between the first space and the second space; and

an inert gas filling the first space, the second space and the vacant space to balance a pressure inside the first space and the atmospheric pressure in order to prevent the first space from deforming, wherein the inert gas is dry nitrogen.

15. (Previously Presented) The semiconductor preserver as claimed in claim 14, wherein after pumping an air out of the first space, the second space and the vacant space, the inert gas fills the first space, the second space and the vacant space.